

The Impacts of BSIM

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TSMC

The Impacts of BSIM

● Outline

- What is BSIM
- Industry standard
- Breadth and depth
- Moving forward

What's in a name of BSIM

● The making of BSIM

- 631 papers in IEEE Explore database by Hu's team
 - ◆ Modeling HC, BV, PT ... etc in late '70 and early '80
 - ◆ 1984: 1st paper on IGFET charge model
- "BSIM" was coined in 1987

Berkeley Short-channel IGFET Model

● The BSIM family

- BSIM, BSIM1-6 – planar MOSFETs
- BSIM-MG, BSIM-CMG, BSIM-IMG – 3D FinFETs
- BSIMSOI, BSIMPD, BSIM-IMG – SOI MOSFETs

BSIM was born

IEEE TRANSACTIONS ON CIRCUITS AND SYSTEMS, VOL. CAS-31, NO. 8, AUGUST 1984

Circuits and Systems Letters

A Compact IGFET Charge Model

BING J. SHEU, DON L. SCHARFETTER, CHENMING HU,
AND DONALD O. PEDERSON

Abstract—A new IGFET charge model, consistent with the recently published Compact Short-Channel IGFET Model [1], [2], is presented. It is

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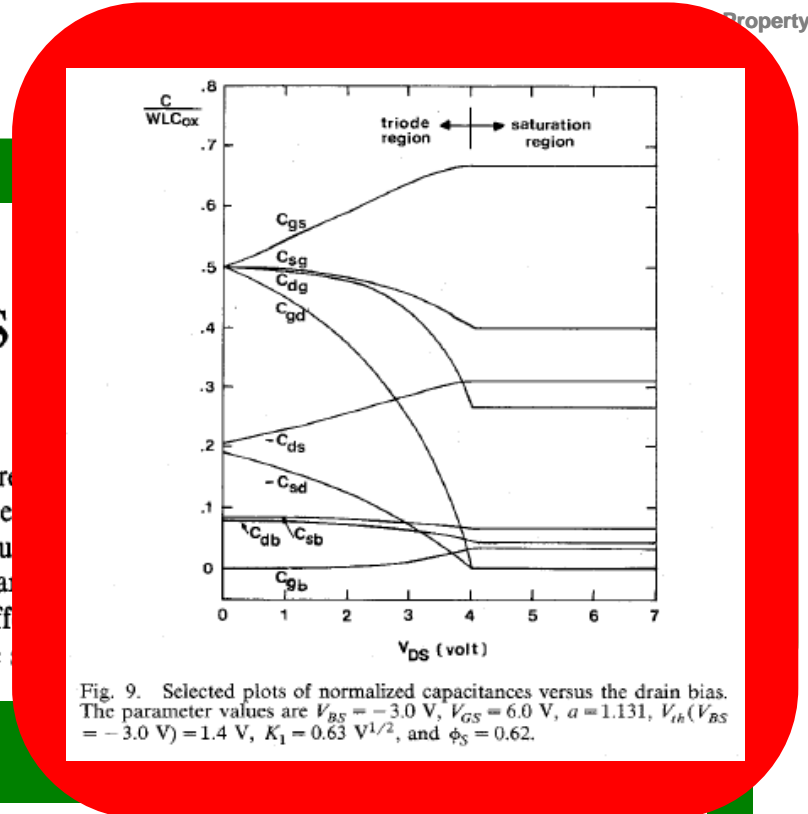


Fig. 9. Selected plots of normalized capacitances versus the drain bias. The parameter values are $V_{BS} = -3.0$ V, $V_{GS} = 6.0$ V, $a = 1.131$, $V_{th}(V_{BS} = -3.0$ V) = 1.4 V, $K_1 = 0.63$ V^{1/2}, and $\phi_S = 0.62$.

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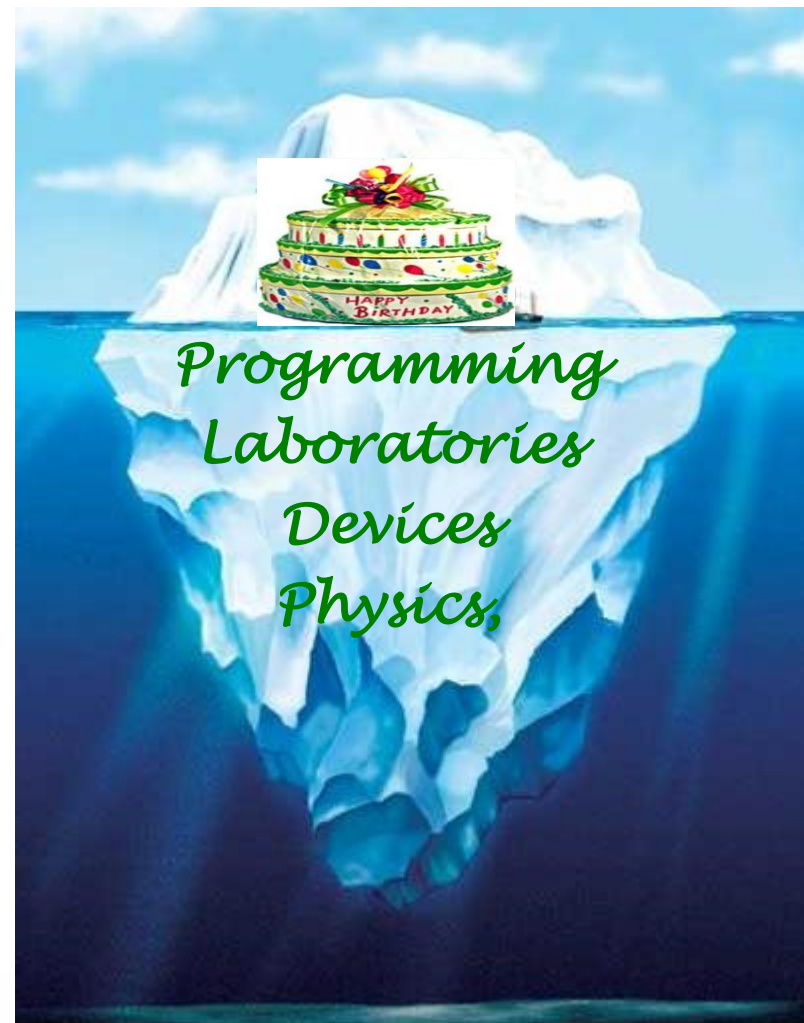
IEEE JOURNAL OF SOLID-STATE CIRCUITS, VOL. SC-22, NO. 4, AUGUST 1987

BSIM: Berkeley Short-Channel IGFET Model for MOS Transistors

BING J. SHEU, MEMBER, IEEE, DONALD L. SCHARFETTER, FELLOW, IEEE, PING-KEUNG KO, MEMBER, IEEE,
AND MIN-CHIE JENG

Tip of an iceberg

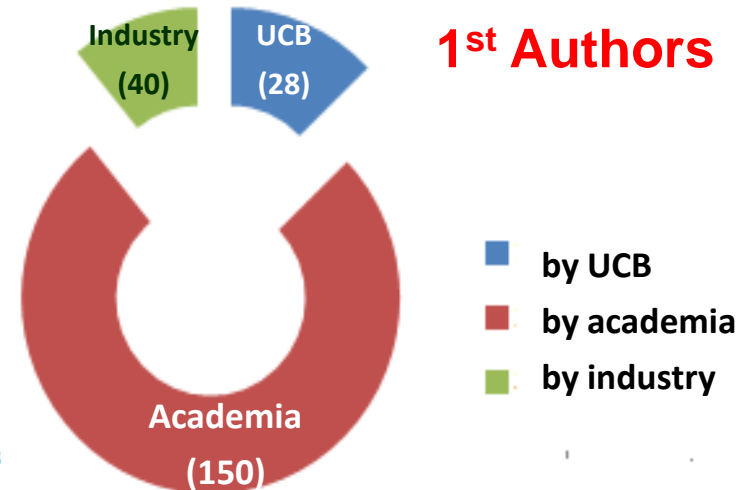
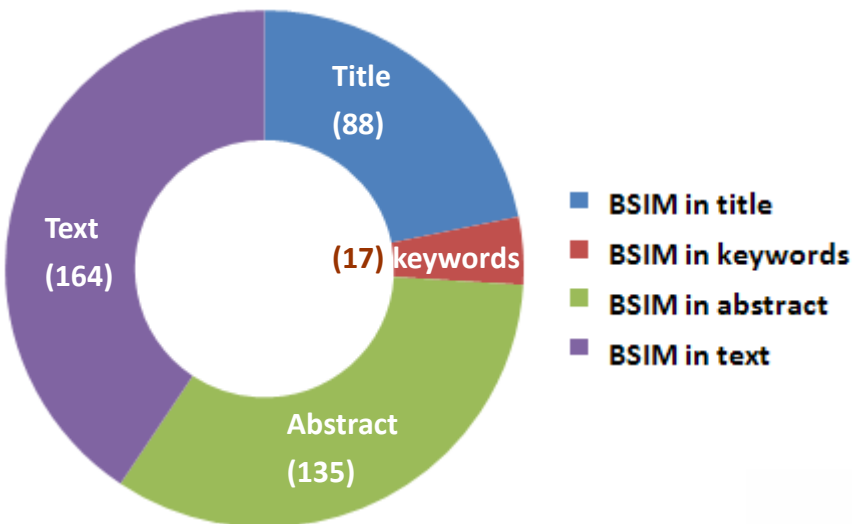
- One team
 - Physics
 - Devices
 - Laboratories
 - Programming
- Academia & industries
 - Evaluations / benchmarking
 - Enhancements / extension
 - Applications / validation



Let the BSIM numbers speak

- More than 200 “BSIM” articles
 - IEEE Explore Database

Honorable mentions

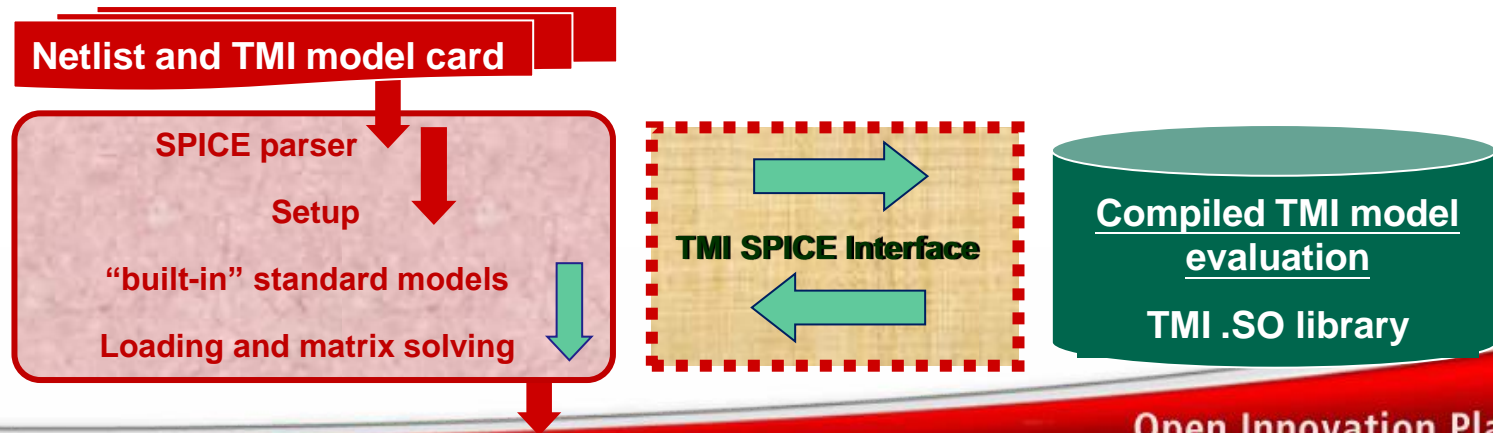


The BSIM standard – the beginning

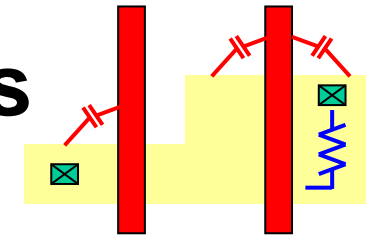
- **Compact model council (CMC) started before 1996**
 - In a time of fragmented compact model development
 - ◆ Though, “de facto standard” MOSFET model exists
 - ◆ Different flavored models in alphabet SPICE’s
 - ◆ IDM’s have their proprietary models & tools
 - ◆ Cross team design hand-shakes were chaotic
- **BSIM3v3 elected as the first CMC standard model**
 - Extensive benchmarking with cross industrial collaboration
 - BSIM team’s dedication is key to its acceptance
- **BSIM4 (2000), BSIMSOI (2002), BSIM-CMG(2012)**
 - Critical nanometer effects
 - Emerging new device structures

The BSIM standard – now and future

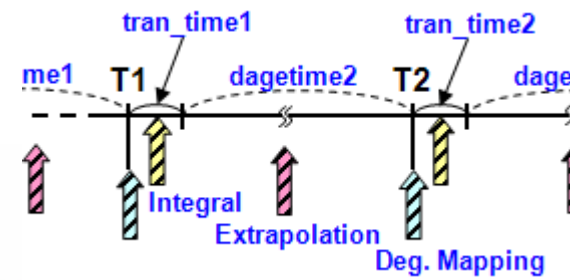
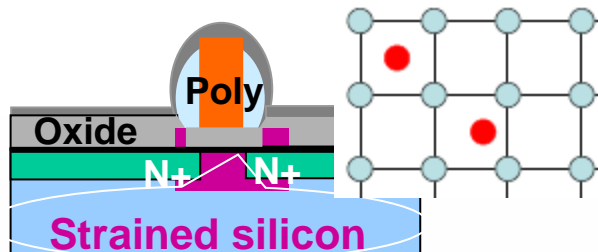
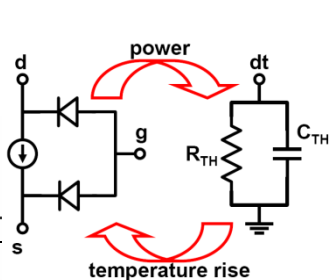
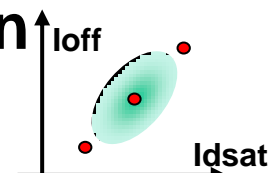
- **BSIM4 : the first CMC standard models in TMI2**
 - **TMI2: the first CMC application program interface (API),2010**
 - ◆ **HSPICE (SNSP), Spectre (CDS), Eldo (MGC)**
- **TMI2 API enables efficient macro modeling**
 - **Macro modeling = intrinsic device + extrinsic effects**
 - ◆ **Layout dependent effects, aging effects, restrict design rules**
 - **Proven efficiency in setup time, memory usage & computing**



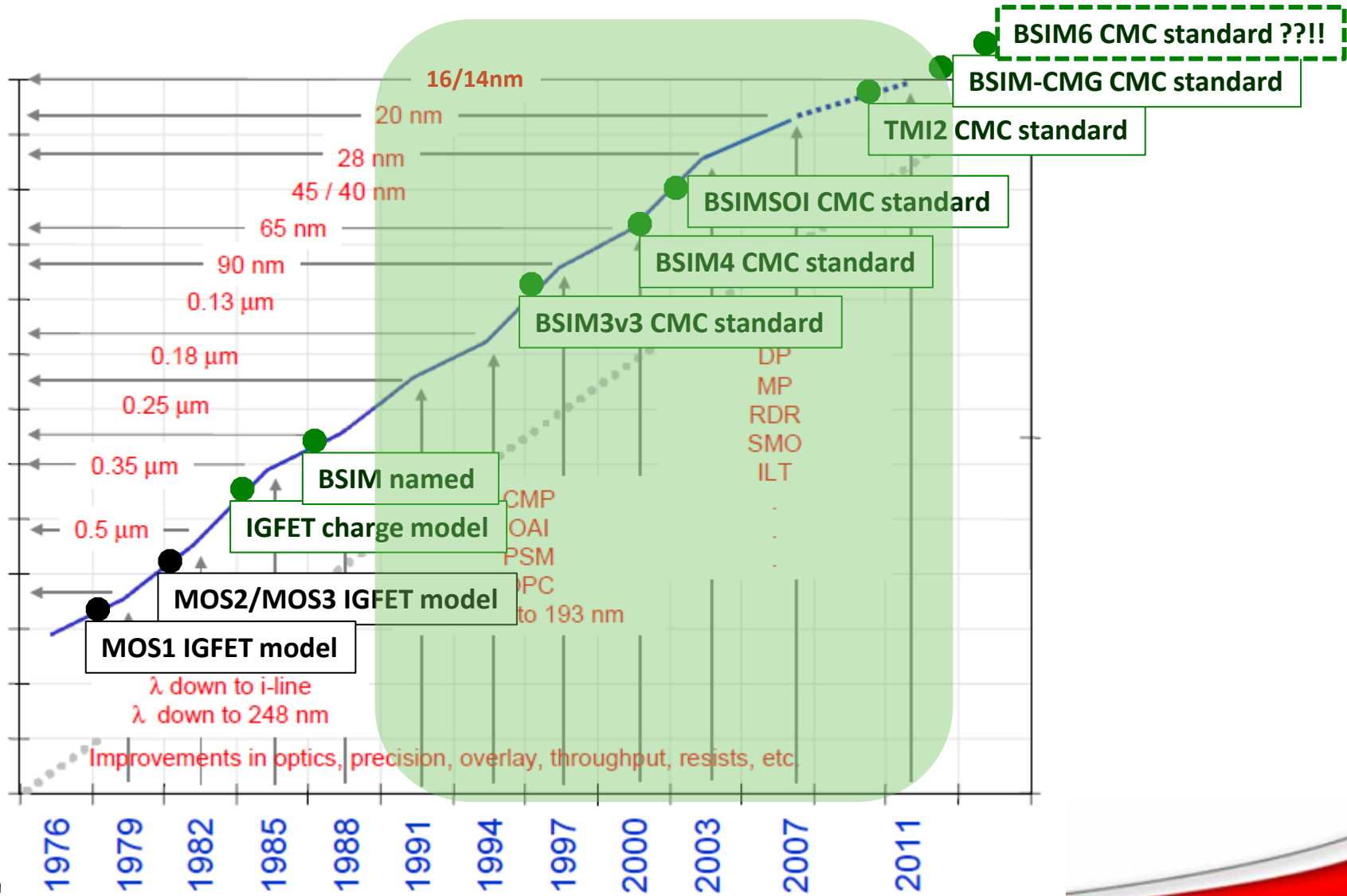
Macro modeling at nanometers



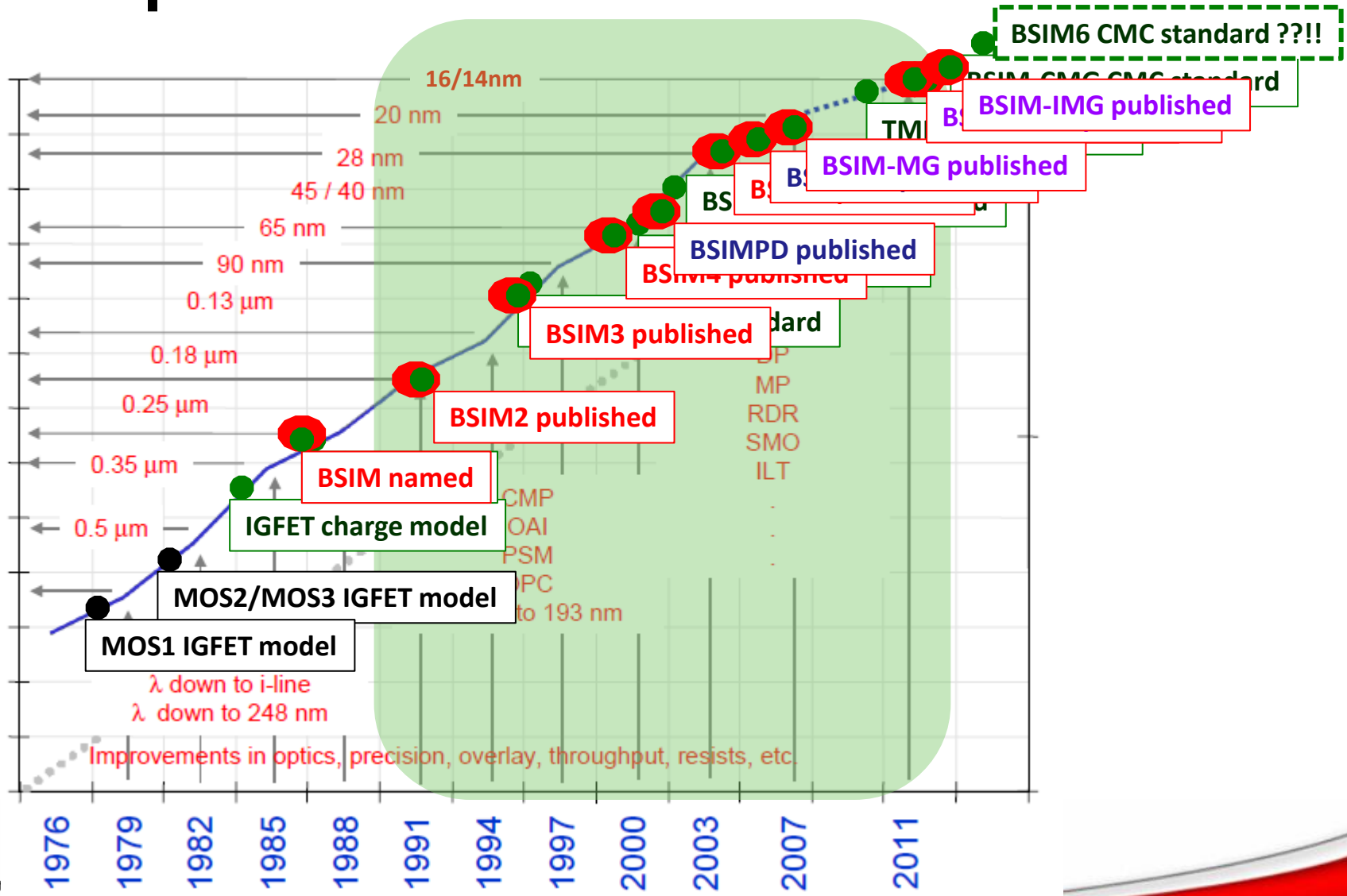
- Complex layout dependency – mechanical stress
- Middle layer (MEOL) effects – device local connects
- Restricted design rules for DFM – new lithography
- Statistical & parametric variations – local & global
- Self-heating effects – a node of device temperature
- Aging effects – age extrapolation & degradation
- Additional geometric scaling – half node ...



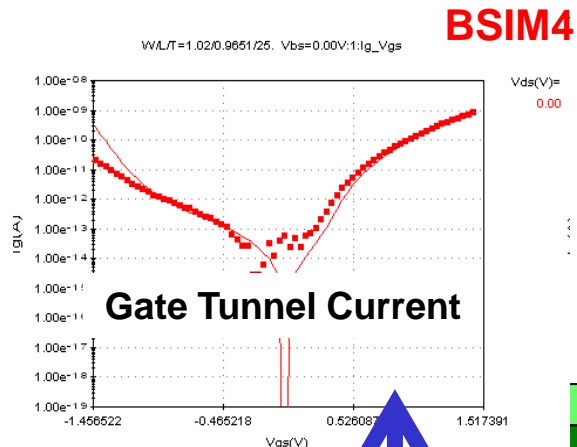
BSIM locomotive



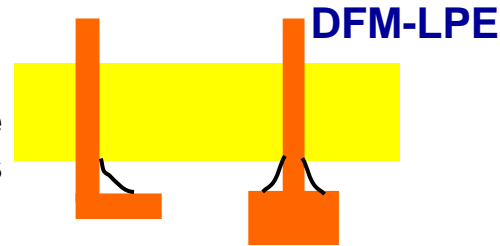
BSIM portfolio



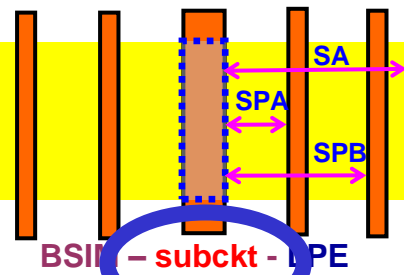
BSIM4 critical features for nanometer



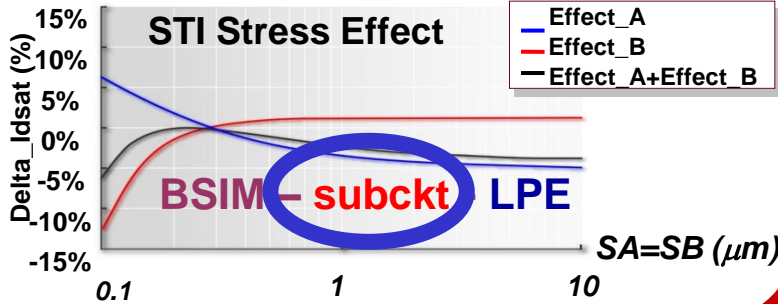
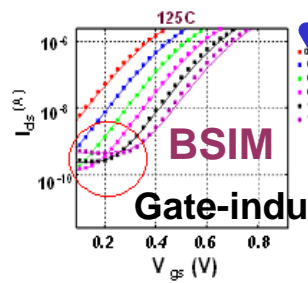
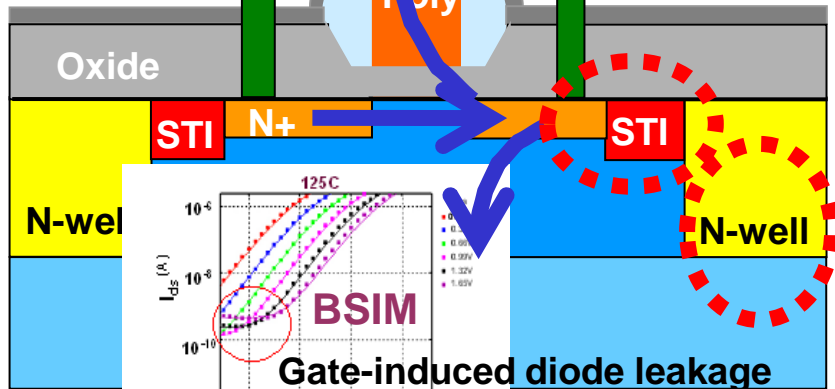
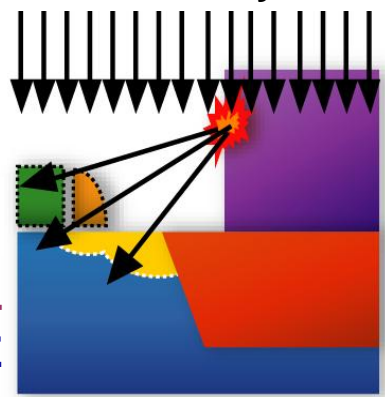
OPC small feature effects



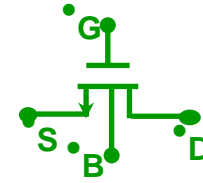
Strained Silicon Stress Effect



Well Proximity



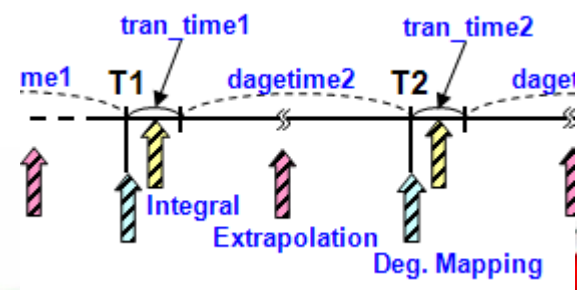
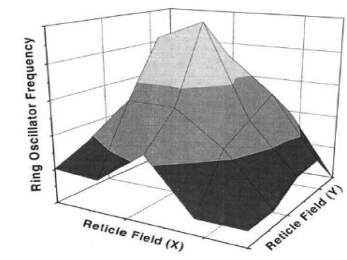
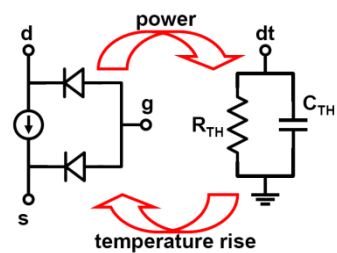
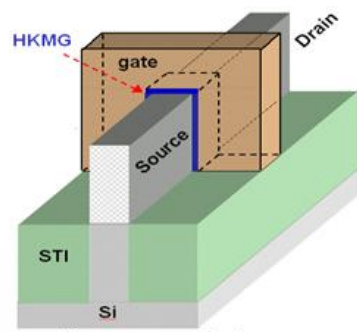
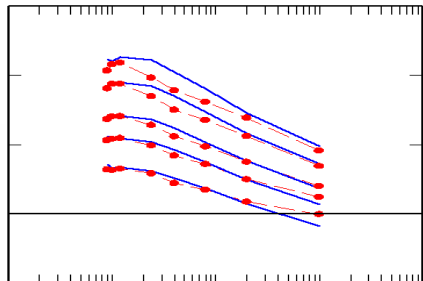
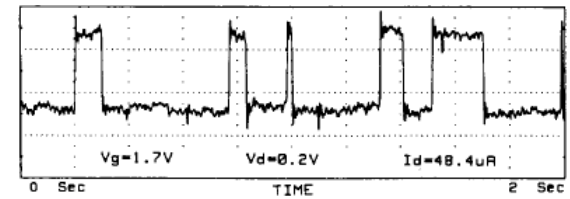
Required basic model features



- Physical and accurate in inversion & accumulation regions
- Relevant small-geometry effects
- Relevant nanometer effects, e.g. halo implant, well-proximity, strained-silicon, shallow-trench stress, ... etc
- Mobility modulation effects, e.g. velocity saturation, Coulomb scattering ... etc
- Quantum-mechanical corrections
- Poly-depletion effects, gate-tunneling & hot-carrier leakage
- Non-quasi saturation (NQS) effects
- Charge /capacitance models conserving electric charge
- Noise models, including flicker and thermal

Emerging effects in deep nanometer

- New device structures – FinFET ...
- Influence from device environment
- Scaling slope changing ...
- Process variation of larger percentage
- Random telegraph noise
- Self heating
- Aging effects



Evolution and revolution

● Foundry deployment

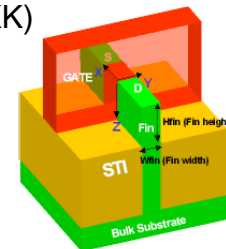
- 2003: Gate tunneling current in BSIM4.3 (90nm)
- 2004: STI stress & trap-assisted diode leakage in BSIM4.4
- 2005: WPE in BSIM4.5 (65nm)
- 2007: Composite STI stress by subckt macro (45/40nm)
- 2008: More new LDE by subckt macro (28/20nm)
- 2011: Aging model & FinFET model in TMI2 for beta testing

● Inventing FinFET

IEDM 1998: “A Folded channel MOSFET for Deep-sub-tenth Micron Era”,

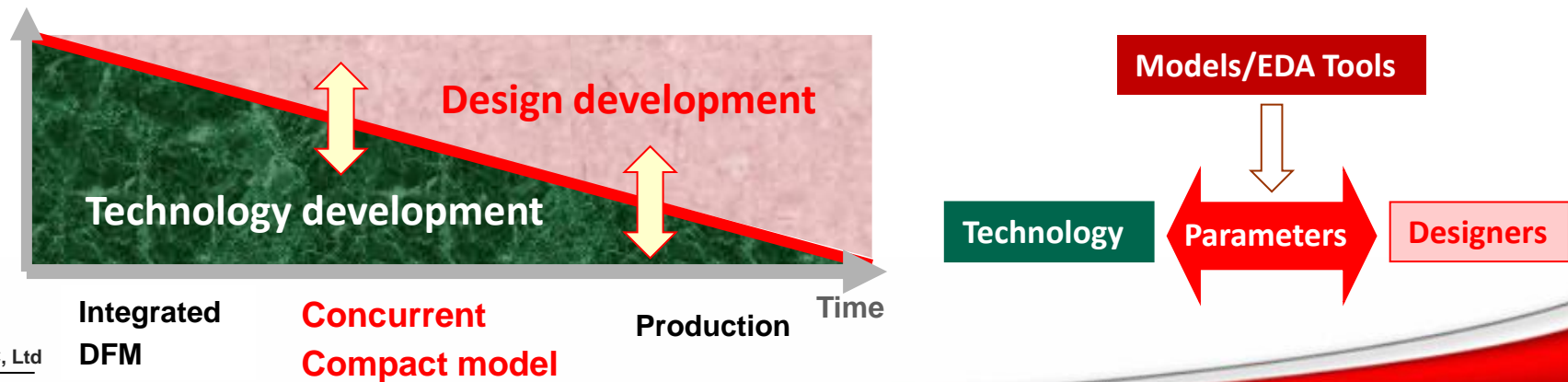
Digh Hisamoto, Wen-Chin Lee, Jakub Kedzierski, Erik Anderson, Hideki Takeuchi, Kazuya Asano, Tsu-Jae King, Jeffrey Bokor, Chenming Hu (Hitachi, UCB, Lawrence Berkeley Lab, Nippon Steel, NKK)

- The viable transistor in sub-20nm
- BSIM-CMG 106.0.0 now a CMC standard model

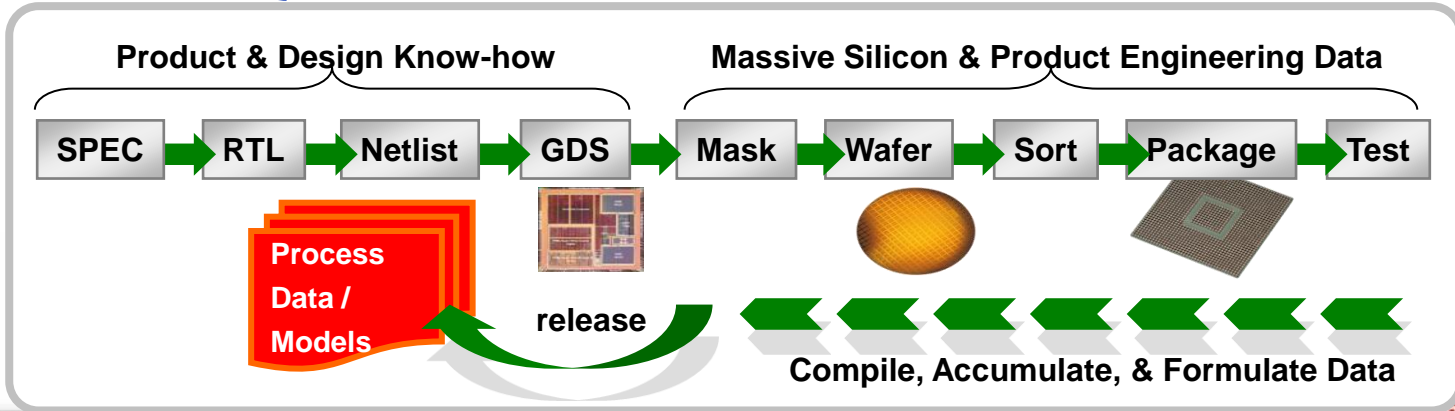
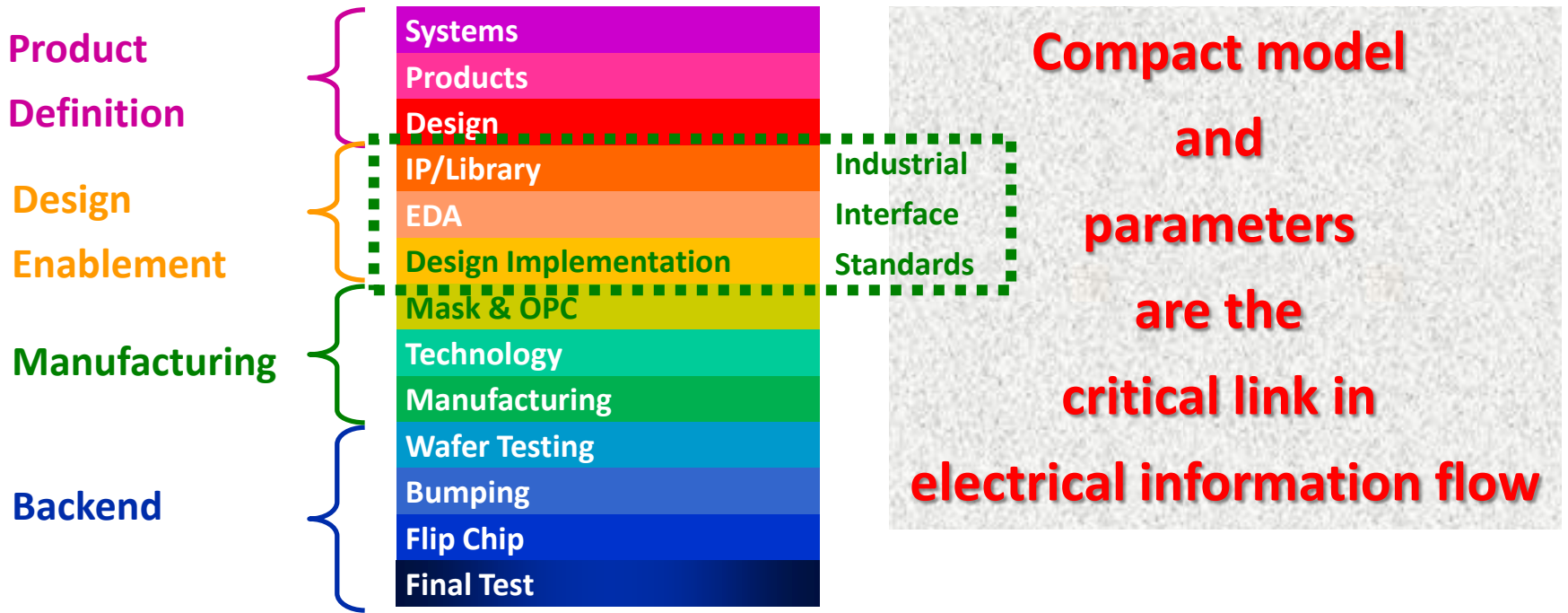


The deep-nano and post-silicon

- **Compact models is pivotal in design enablement**
 - More intensive collaboration between foundry & design
 - Early waves starts earlier
- **Standard model and standard API key to deployment**
 - Standard models definitely for device intrinsic behaviors
 - Macro-modeling definitely for surrounding influences

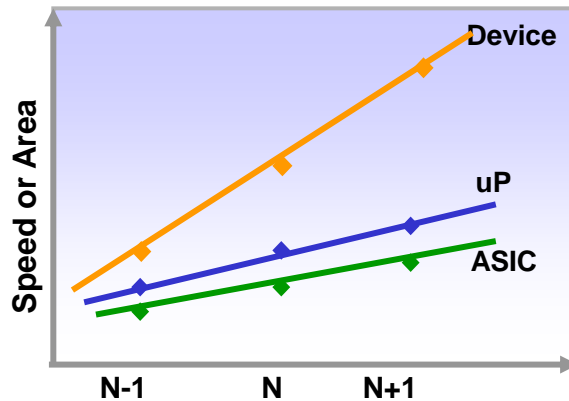


Semiconductor eco-system

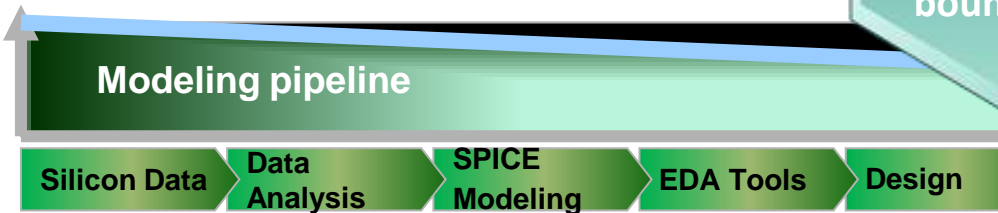


The best yet to come

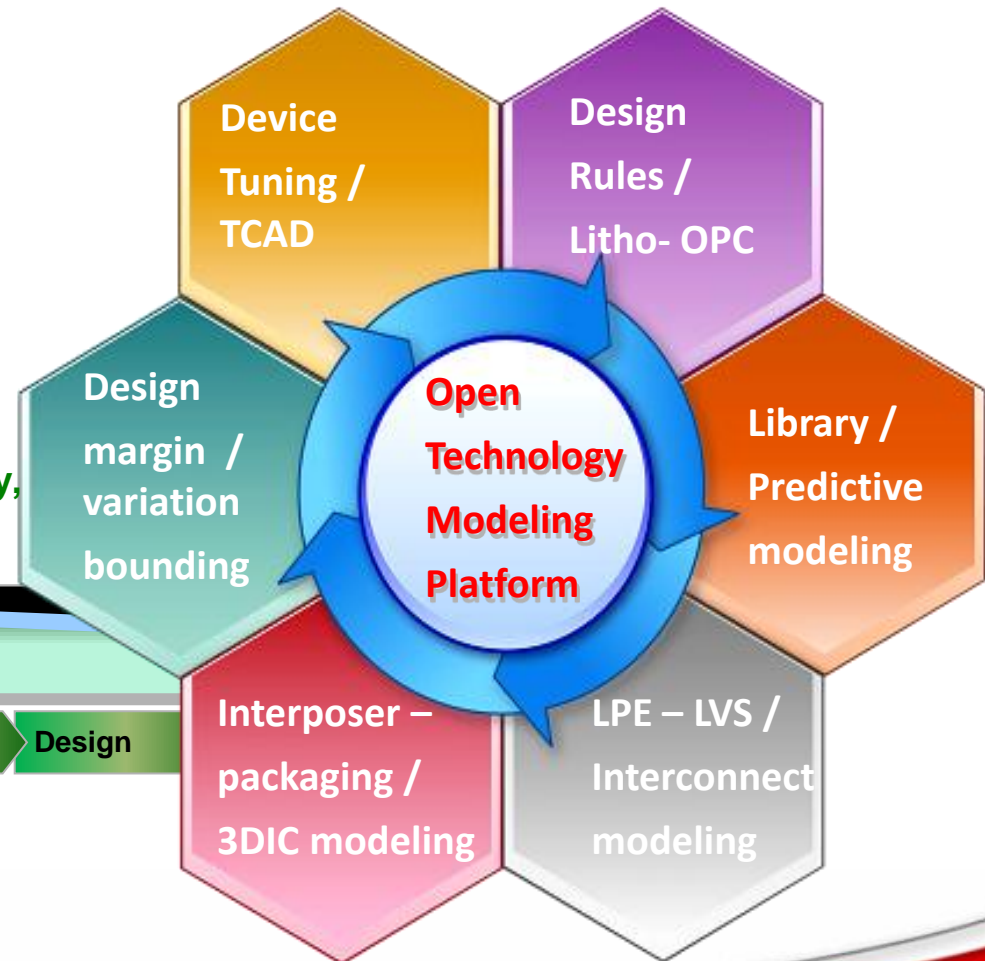
An Eco-System for Innovations



“ET” delivers performance, manufacturability, reliability in scaled dimensions



- “New / Changes” is the norm
 - ✓ New devices, new materials, new litho, new constraints,
 - ✓ Rapid recipe changes as ET evolves / revolves



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contribution in advancing compact models at foundry**